

Amendment and Response

Applicant: Norman L. Oberski et al.

Serial No.: 10/6232,848

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Docket No.: A126.113.102

Title: INSPECTION TOOL WITH A 3D POINT SENSOR TO DEVELOP A FOCUS MAP

IN THE ABSTRACT

Please replace the paragraph beginning at page 9, line 4, with the following, re-written paragraph:

Abstract of the Disclosure

An inspection system, and process for use thereof, allows for inspecting of semiconductors or like substrates. The inspection system includes an inspection device and an auxiliary sensor apart from the inspection device. The auxiliary sensor is used to collect height data and generate a map of a semiconductor or like substrate to aids in focusing the inspection device.